**Docket Number** AMENDMENT TRANSMITTAL LETTER GOM-02001 Application Number Filing Date Examiner **Group Art Unit** 09/8 3,972 1762 March 27, 2001 Anna Crowell Invention Title MÉTHOD OF FORMING SILICON OXIDE FILM AND FORMING APPARATUS THEREOF TO THE COMMISSIONER FOR PATENTS Transmitted herewith is an amendment in the above-identified application, including: Amendment and Response; (X) Postcard Receipt **CLAIMS AS AMENDED** (1) (2) (3)**CLAIMS HIGHEST PRESENT** RATE FEE REMAINING NUMBER NUMBER **AFTER PREVIOUSLY EXTRA AMENDMENT** PAID FOR **TOTAL CLAIMS** 14 minus 20 0 x \$18 \$0 INDEPENDENT CLAIMS 3 minus 3 0 x \$86 \$0 MULTIPLE DEPENDENT \$290 **CLAIM ADDED TOTAL** \$0 If applicant has small entity status under 37 CFR 1.9 and **SMALL ENTITY TOTAL** 1.27, then divide total fee by 2, and enter amount here. If the entry in column 1 is less than the entry in column 2, write "0" in column 3. If the highest number previously paid for IN THIS SPACE is less than 20, enter "20." If the highest number previously paid for IN THIS SPACE is less than 3, enter "3." The "highest number previously paid for" (total or independent) is the highest number found in the appropriate box in column 1. Please charge Deposit Account Number 03-1721 in the amount of \$\_ duplicate copy of this sheet is enclosed. A check in the amount of \$ to cover the filing fee, (X) Please credit any overpayment and/or charge any additional filing fees required under 37 CFR §§ 1.16 and 1.17 to our Deposit Account Number 03-1721. A duplicate copy of this sheet is enclosed.

Donald W. Muirhead, Reg. No. 33,978

November 12, 2003

Date (10-95) I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on this 12<sup>th</sup> day of November, 2003.

Tracev A. Newell

Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

pplication of:

Appl. No.: 09/818,972

Filed: March 27, 2001

Katsuhisa YUDA, et al.

Art Unit: 1762

Examiner: Anna Crowell

Atty Docket: GOM-02001

For: METHOD OF FORMING SILICON

OXIDE FILM AND FORMING APPARATUS THEREOF

## **CERTIFICATE OF MAILING**

I hereby certify that the foregoing document is being deposited with the United States Postal Service as first class mail, postage prepaid, "Post Office to Addressee", in an envelope addressed to: Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on November 12, 2003.

## AMENDMENT AND RESPONSE TO OFFICE ACTION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

This paper is being provided in response to the Office Action dated August 14, 2003 for the above-captioned U.S. patent application.

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

**Remarks** begin on page 7 of this paper.

It is not believed that extensions of time or fees for net addition of claims are required, beyond those which may otherwise be provided for in documents accompanying this paper. However, in the event that additional extensions of time are necessary, then such extensions of time are hereby petitioned under 37 C.F.R. § 1.136(a), and any fees required for consideration of this paper (including fees for net addition of claims) are authorized to be charged in two originally-executed copies of an Amendment Transmittal Letter filed herewith.